

TEST OF A CONFOCAL MULTILAYER



X-RAY OPTIC

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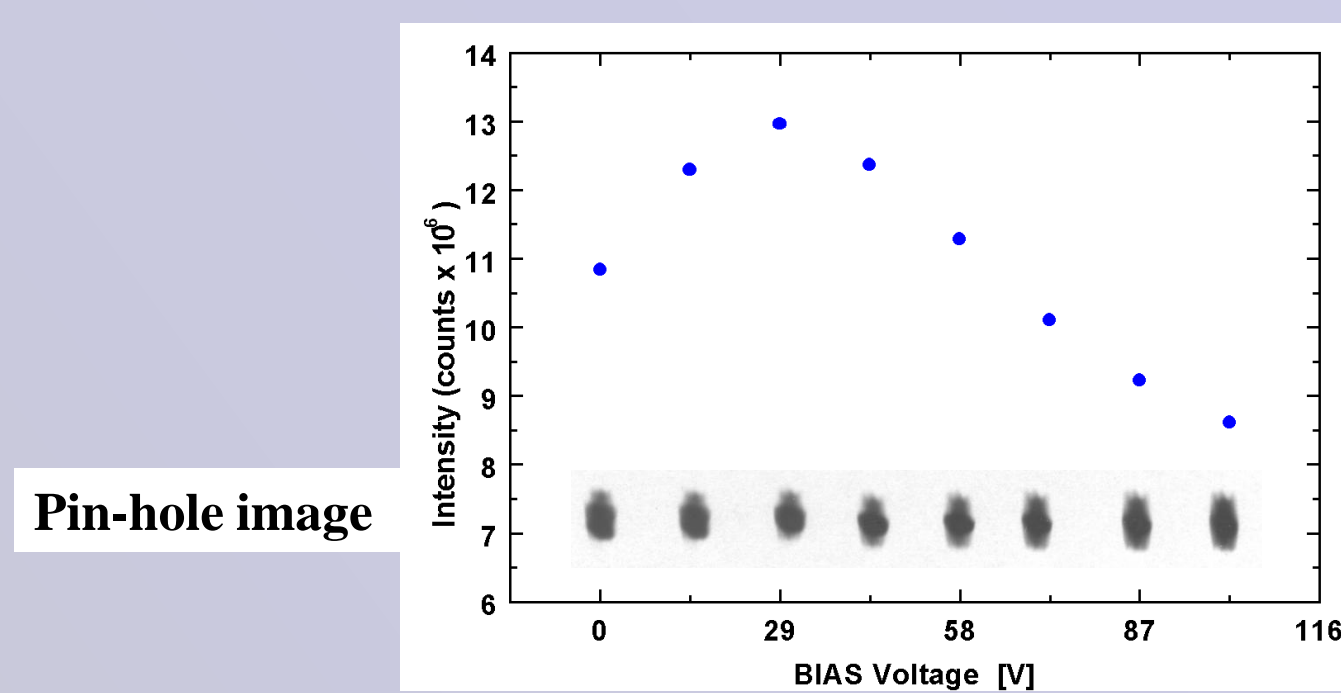
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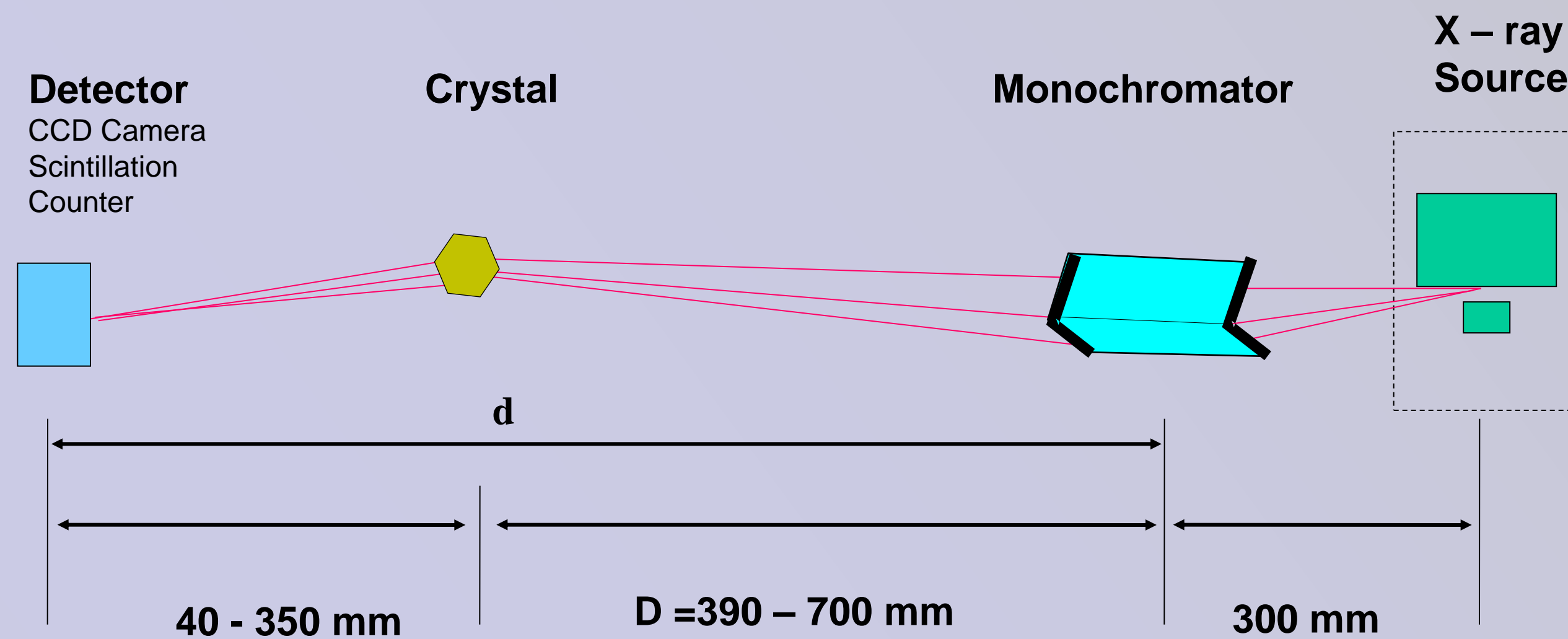
X-Ray Source

SCHNEIDER® Rotating Anode Generator:
Mo – and Cu –Radiation, 5.5 kW
Spot Focus: 0.3 x 3 mm²



Intensity for different values of the bias voltage [V]

Experimental Set-up



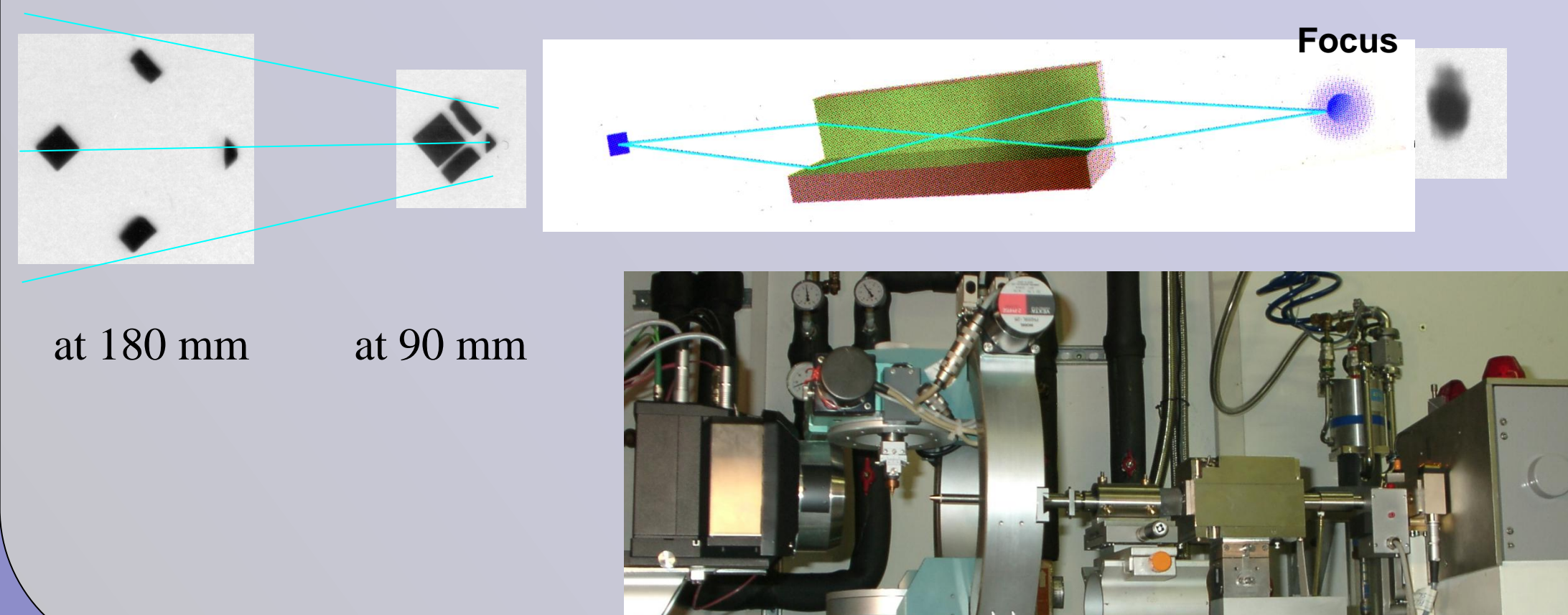
Comparison of two Foci

Focus test with an ENRAF-NONIUS rotating anode
CuK α , 35 kV

Size mm ²	Power kW/mA	Powerdensity kW/mm ²	Intensity counts
0.1x1	1.2/34	12	2900
0.3x3	3/85	3.3	4100
Ratio	2.5	0.23	1.44

Monochromator

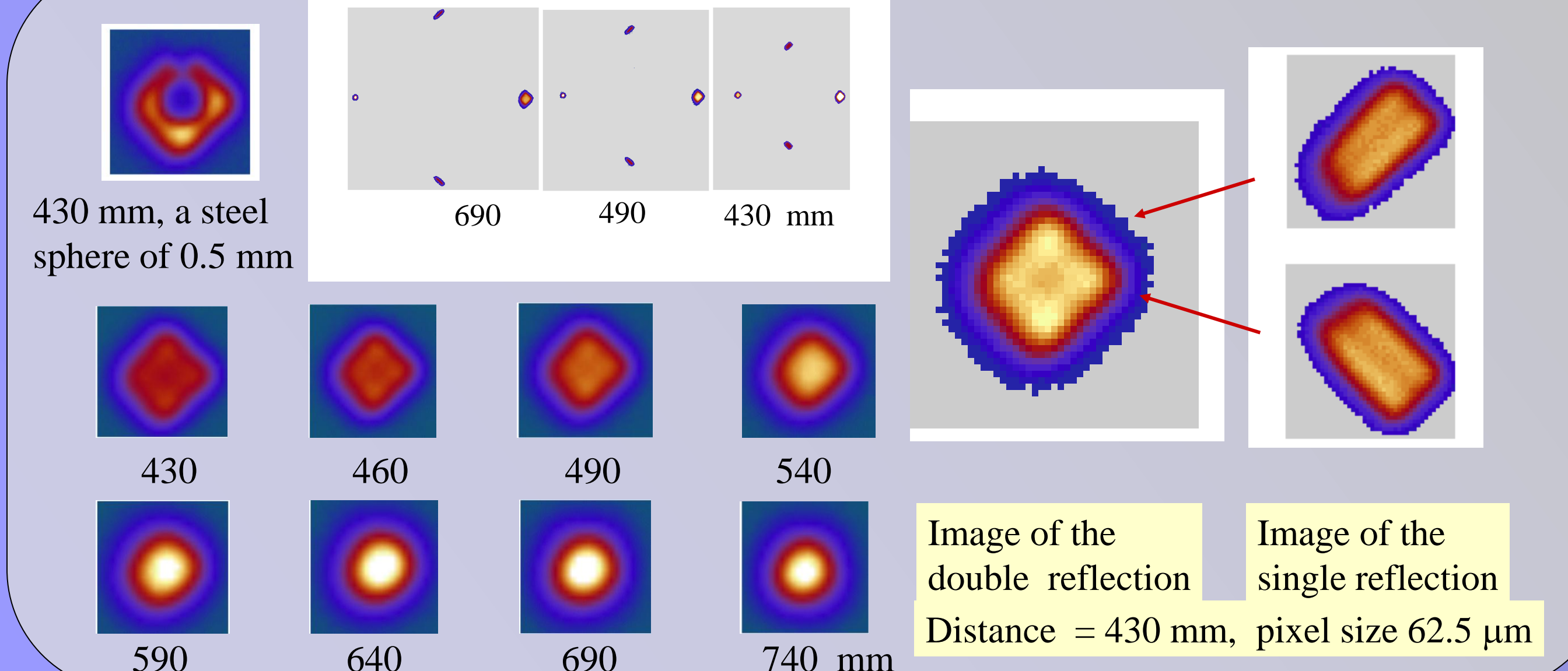
Confocal graded multilayer optic of OSMIC ©Inc.



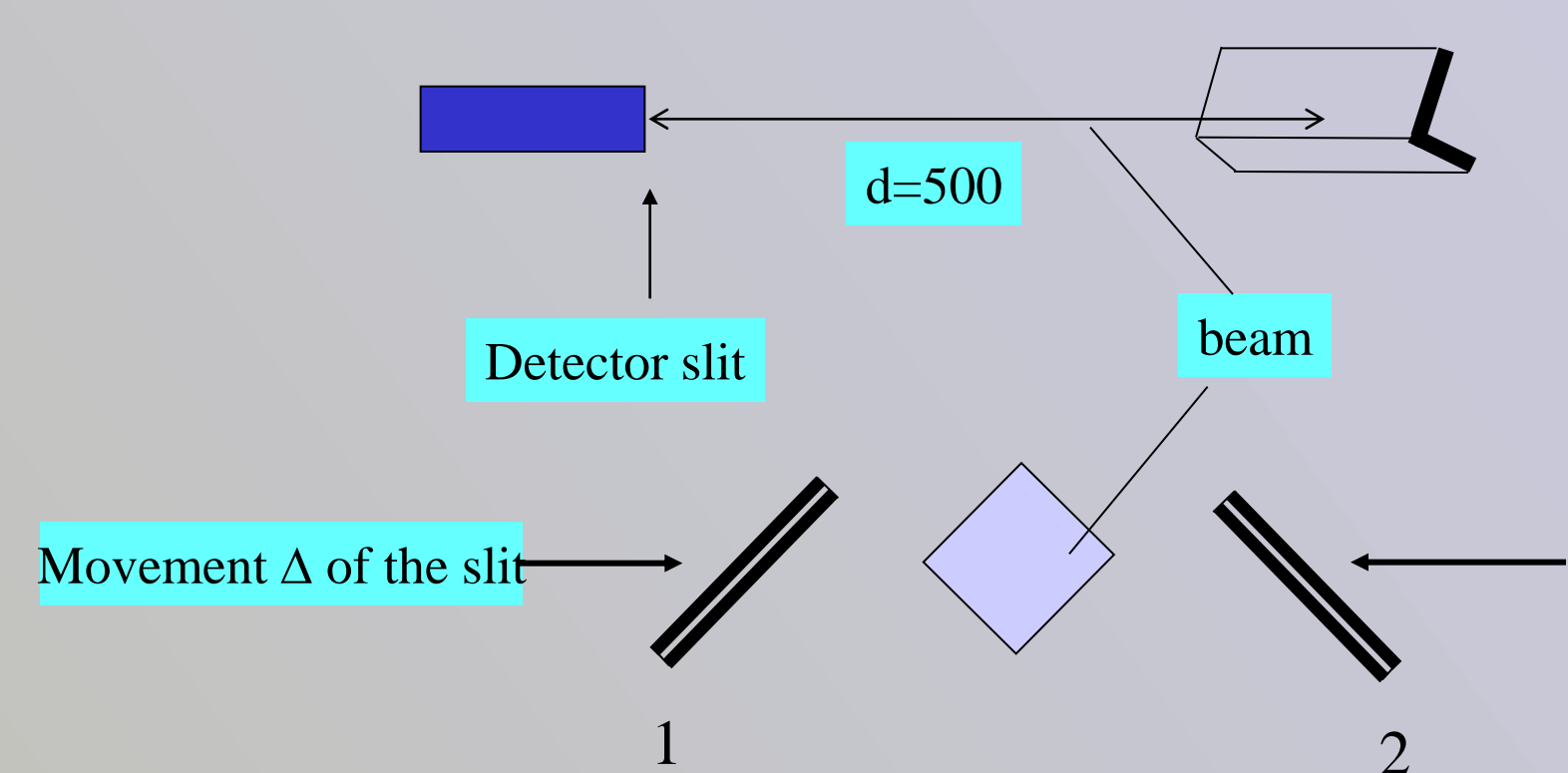
Technical Data from the data sheet of OSMIC ©Inc :

Major radius a: 502.5 mm
Minor radius b: 11.8 mm
Position of the mirror : -202.5 mm
Length of the optic : 100 mm
Focal to focal distance: 1005 mm
Distance between Source and optic : 300 mm
side – by – side geometry
horizontal beam geometry (45 ° inclination)

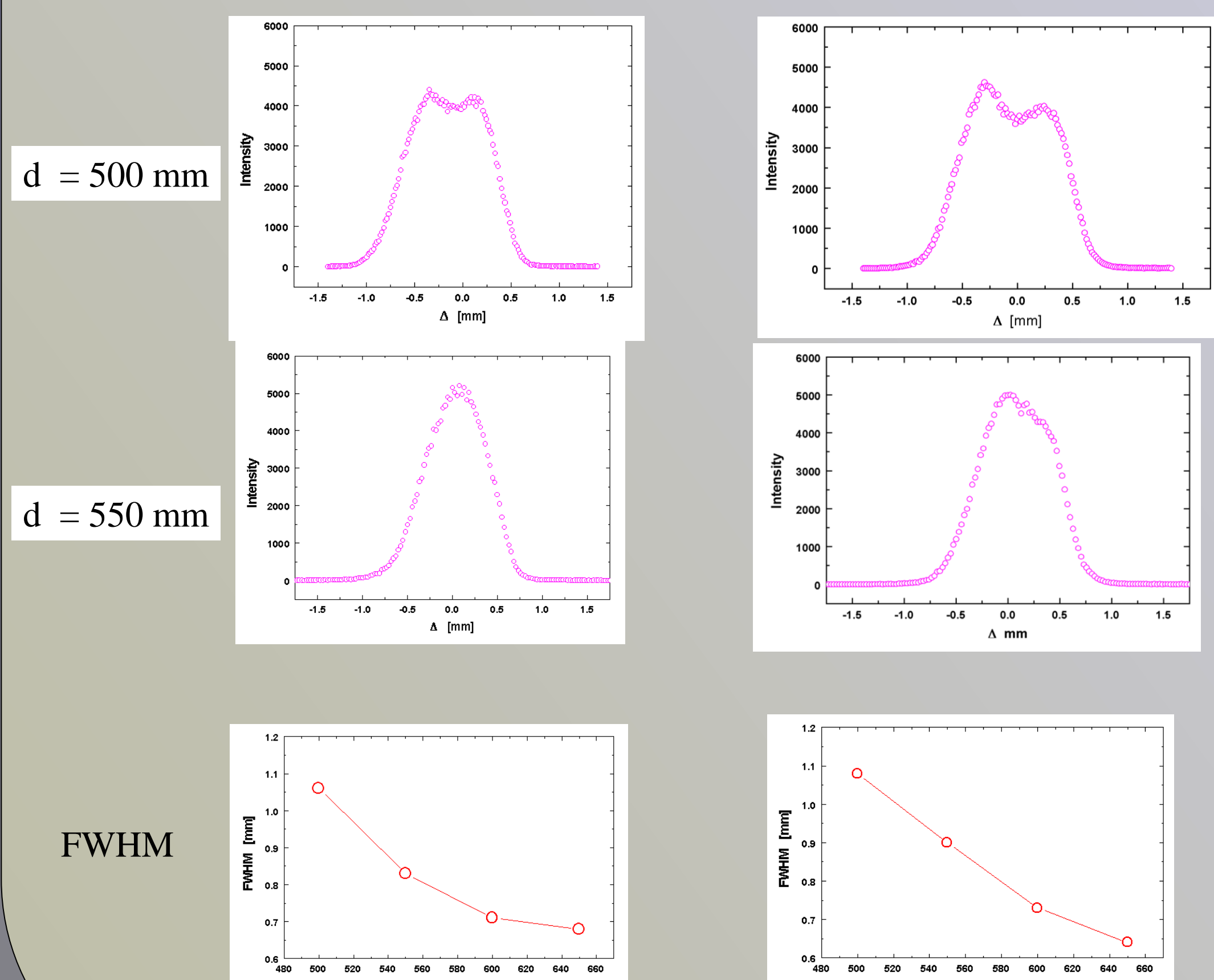
Variation of the Distance d from the Optic



Scan of the Beam: Profile

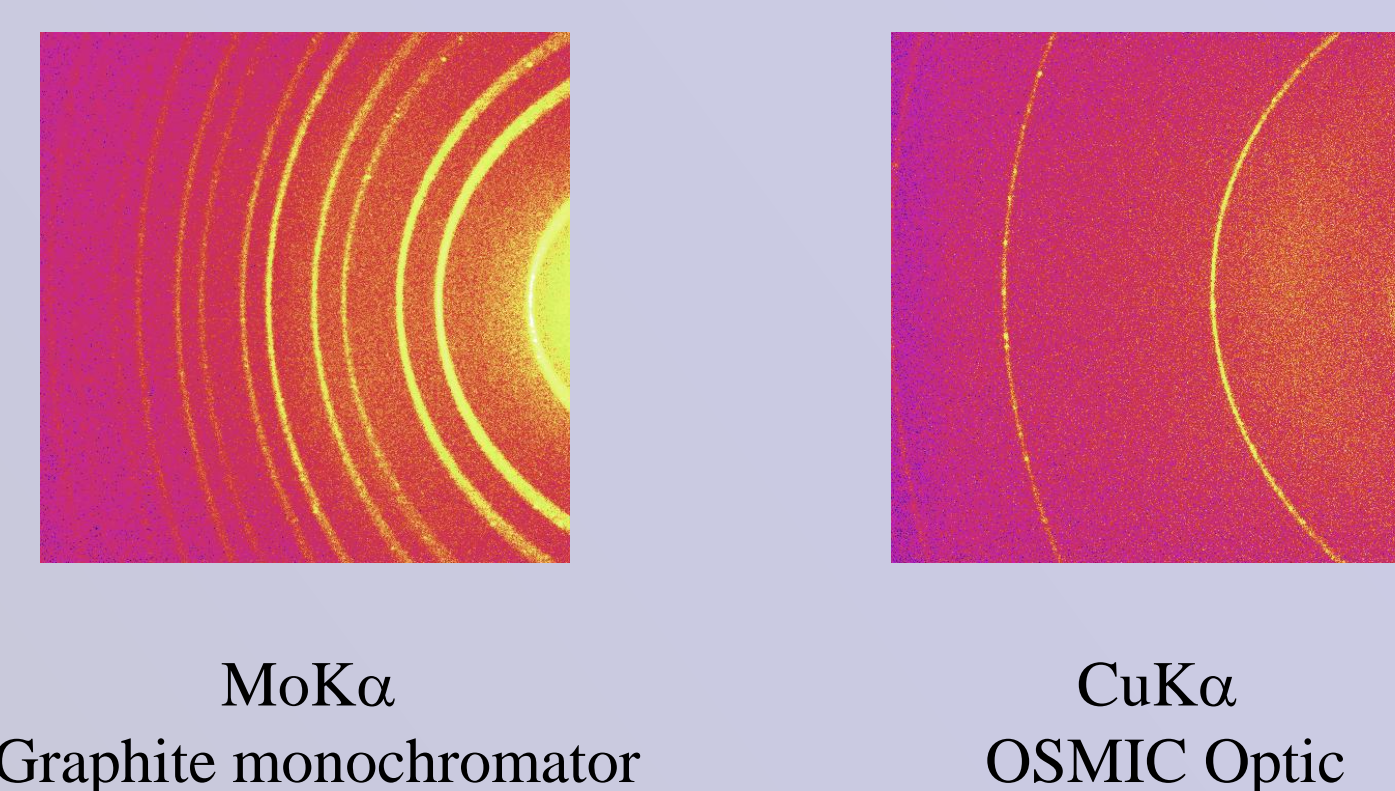


Slit of the detector was put into two positions;
scan was performed by moving the slit in the indicated direction

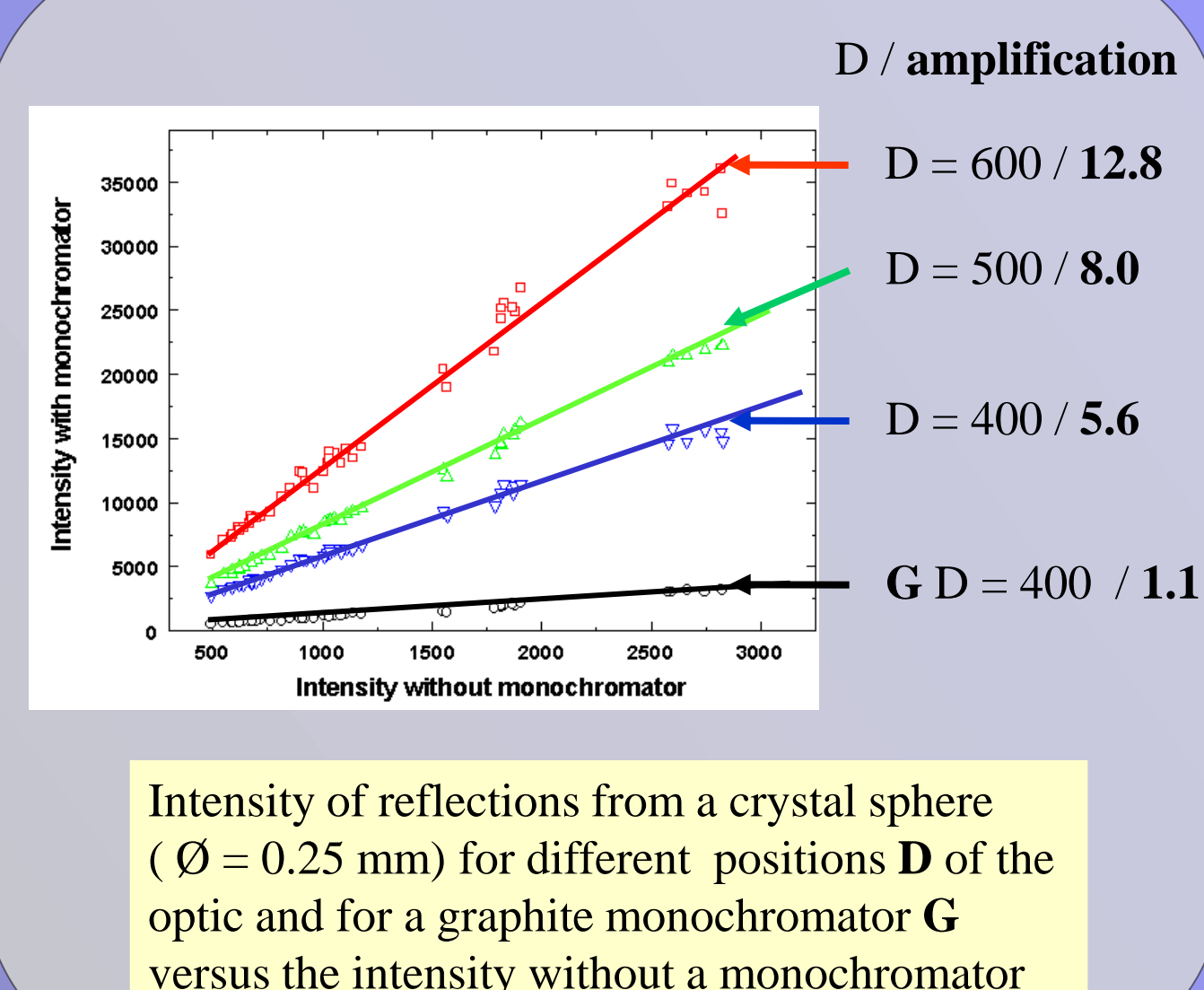


Powder sample

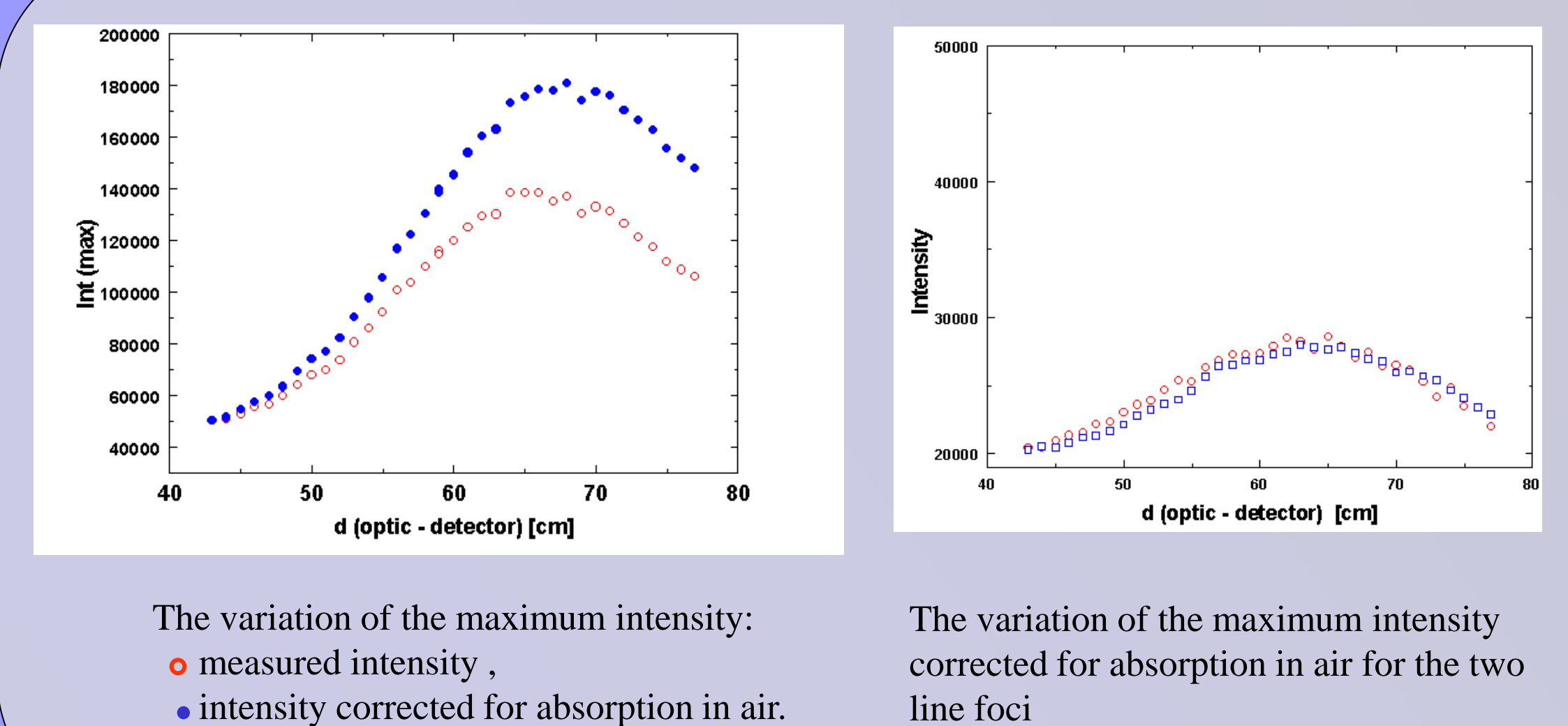
A powder sample (Si-powder) in a capillary ($\varnothing = 0.3$ mm)
is placed at the position of the single crystal.



Comparison



Intensity versus Distance



Conclusion

The performance of the multilayer optic :

- Optimum performance for a spot focus 0.3 x 3 mm
- Homogeneous profile for $D > 500$ mm
- Optimum crystal position with maximum gain depends on the size of the crystal (flexible positioning of the diffractometer).
- Sharp lines with high resolution for powder samples (very useful with a CCD detector for materials with big lattice parameters)
- Precise determination of lattice parameters for single crystals.
- Useful application for metric changes at phase transitions
- Measurements of diffuse intensities.
- Measurements of sputtered thin films

References

"Confocal Max-Flux™ Optic", OSMIC Inc., Troy, Michigan, USA
J. Schneider Elektrotechnik GmbH, D-77652 Offenburg, Germany